

Application No. 10/005,188

AMENDMENTS TO THE CLAIMS

A detailed listing of all claims that are, or were, in the present application, irrespective of whether the claim(s) remains under examination in the application are presented below. The claims are presented in ascending order and each includes one status identifier. Those claims not cancelled or withdrawn but amended by the current amendment utilize the following notations for amendment: 1) deleted matter is shown by strikethrough for six or more characters and double brackets for five or less characters; and 2) added matter is shown by underlining.

1. (Previously Presented) A wafer container system comprising:
 - a) a container portion with an open front, a top, and a bottom;
 - b) a door for closing the open front;
 - c) a machine interface on the bottom of the container portion, the machine interface having a first configuration;
 - d) a receptacle portion on the top of the container portion; and
 - e) a stacking adaptor plate for releasable engagement with the container portion at the receptacle portion, the stacking adaptor plate configured to cooperate with a machine interface with the first configuration.
2. (Previously Presented) The wafer container system of claim 1, wherein the stacking adaptor plate has at least three rounded projections and a detent for latching onto the container portion at the receptacle portion.

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3. (Previously Presented) The wafer container system of claim 2, wherein the stacking adaptor plate has three container portion contact portions extending downwardly and positioned proximate the at least three rounded projections.
4. (Original) A stacking adaptor plate for stacking a plurality of wafer containers, the containers each having a top, and a bottom with a kinematic coupling thereon, the stacking adaptor plate adapted to fit on the top of the wafer container to facilitate stacking of the plurality of wafer containers and having an upwardly facing kinematic coupling portion.
5. (Original) The stacking adaptor plate of claim 4 wherein the adaptor plate has a detent for removably attaching the plate to wafer containers.
6. (Original) A wafer container system comprising a container portion having a plurality of slots therein for holding a plurality of wafers, the container portion further comprising a top, a bottom, a machine interface positioned at the bottom, and an adaptor plate conformed to engage with the top of the wafer container, the adaptor plate comprising at least three rounded projections comprising one portion of a kinematic coupling.
7. (Currently Amended) The ~~stacking~~ adaptor plate of claim ~~[[4]]~~ 6 wherein the adaptor plate has a detent for removably attaching the plate to wafer containers.

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8. (Original) The stacking adaptor plate of claim 6 wherein the plate further comprises three legs extending horizontally and spaced equally from one another.

9. (Previously Presented) The stacking adaptor plate of claim 6 wherein the plate has three legs extending horizontally with at least one of said legs having one of the at least three rounded projections.

10. (Currently Amended) A wafer container system comprising a pair of wafer containers, each of said pair of wafer containers comprising a container portion having a plurality of slots therein for holding a plurality of wafers, ~~the container portion further comprising~~ a top, a bottom, a machine interface positioned at the bottom, and a stacking adaptor plate at the top of each of said wafer containers ~~the wafer container~~, the machine interface comprising three grooves as ~~[[one]]~~ a first cooperating part of a kinematic coupling, the adaptor plate comprising at least three rounded projections comprising ~~[[the]]~~ a second cooperating part of ~~another part of~~ said kinematic coupling, whereby ~~a plurality of pairs~~ said pair of said wafer containers may be stacked together with said ~~two~~ first cooperating part ~~parts of~~ said kinematic coupling intermediate ~~each said adjacent~~ pair of wafer containers.

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11. (Previously Presented) A stack of wafer carriers, the wafer carriers each comprising a container portion with an open front, a door to close the open front, a three groove kinematic coupling fixed to the bottom of the container portion, an adapter plate inserted between each of the stacked wafer carriers, the adaptor plate comprising at least three upwardly extending projections engaged with the three groove kinematic coupling of the wafer carrier immediately above said plate, and the adaptor plate engaged with the top of the container portion immediately there below.

12. (Previously Presented) The stack of wafer carriers of claim 11, wherein the adaptor plate has a detent projecting therefrom for removable attachment to the wafer carrier therebelow.

13. (Currently Amended) A method of stacking first and second wafer carriers, the first and second wafer carriers each comprising a container portion with an open front, a door to close the open front, a three groove kinematic coupling ~~fixed to~~ disposed proximate the bottom of the container portion, and a carrier portion disposed proximate a top of the container portion, the method comprising the steps of:

inserting between ~~each two of the first and second~~ first and second wafer carriers an adaptor plate having a three projection kinematic coupling extending upwardly for engagement with the three groove kinematic coupling disposed proximate the bottom of the first wafer container thereabove, and

engaging each of the adaptor plates plate with the carrier portion of the second wafer carrier ~~immediately therebelow~~.

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14. (Currently Amended) The method of claim 13 further comprising the step of engaging each said adaptor plate with the second wafer container ~~therebelow~~ by way of a detent extending from the adaptor plate.